

CLAIMS

1. A method of forming a conductor wiring pattern, comprising the following steps of:
 - forming a first insulating layer on a surface of a substrate and also forming a second, photosensitive insulating resin layer thereon;
 - light-exposing and developing the second insulating layer to form pattern grooves so that the first insulating layer is exposed at bottoms of the pattern grooves;
 - forming a plating seed layer on the second grooves and then forming inner surfaces of the pattern grooves except for portions of the pattern grooves; seed layer as a power supply layer; and filling the pattern grooves with a conductor by an electrolytic plating using the plating seed layer as a power supply layer; and removing the resist pattern and also second insulating layer to form wiring grooves.
2. A method as set forth in claim 1, wherein a plurality of different metal layers are used, as the conductor, when the pattern grooves are filled with the conductor by the electrolytic plating.
3. A method as set forth in claim 2, wherein the plurality of different metal layers are filled with the metal layers consisting of a copper base layer and a nickel barrier layer.
4. A method as set forth in claim 1, wherein the first insulating layer is composed of a photosensitive insulating resin;
 - after the first insulating layer is light-exposed and developed to form an opening, through which a first wiring pattern formed on the substrate is to be electrically connected to a second wiring pattern to be formed on the first insulating layer, the first

insulating layer is heated and hardened.

5 5. A method as set forth in claim 1, wherein a semiconductor wafer is used as the substrate, the semiconductor wafer has an electrode terminal forming surface, on which the first insulating layer and the second insulating layer are formed, and the wiring pattern, which is electrically connected with electrode terminals of the semiconductor wafer, is formed.